

L Number	Hits	Search Text	DB	Time stamp
-	3433	aluminum and (over\$etch or over\$etching or (over adj etch) or (over adj etching))	USPAT	2003/08/04 12:01
-	506	aluminum same(over\$etch or over\$etching or (over adj etch) or (over adj etching))	USPAT	2003/08/04 15:33
-	506	aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))	USPAT	2003/08/04 09:43
-	29	(aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and (feed\$1back)	USPAT	2003/08/04 09:46
-	463	(aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor	USPAT	2003/08/04 09:47
-	268	((aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor) and (control\$3)	USPAT	2003/08/04 15:34
-	268	((((aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor) and (control\$3)) and @ay<=2001	USPAT	2003/08/04 13:45
-	81	((((aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor) and (control\$3)) and @ay<=2001) and (measure or measuring or sensor or model)	USPAT	2003/08/04 15:35
-	1	6136721.pn.	USPAT	2003/08/04 10:38
-	1	6136721.pn. and aluminum and overetching	USPAT	2003/08/04 10:52
-	101	Subramanian-Ramkumar.in.	USPAT	2003/08/04 14:17
-	99	Subramanian-Ramkumar.in. and semiconductor	USPAT	2003/08/04 10:53
-	43	(Subramanian-Ramkumar.in. and semiconductor) and aluminum	USPAT	2003/08/04 10:53
-	4	Subramanian-Ramkumar.in. and @py<=2000	USPAT	2003/08/04 10:53
-	187	((((aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor) and (control\$3)) and @ay<=2001) not (((((aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor) and (control\$3)) and @ay<=2001) and (measure or measuring or sensor or model))	USPAT	2003/08/04 10:55
-	78	((((aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor) and (control\$3)) and @ay<=2001) not (((((aluminum same (over\$etch or over\$etching or (over adj etch) or (over adj etching))) and semiconductor) and (control\$3)) and @ay<=2001) and (measure or measuring or sensor or model))) and (chamber or apparatus)	USPAT	2003/08/04 12:00
-	113	156/345.33.ccls.	USPAT	2003/08/04 12:00
-	8	156/345.33.ccls. and (over\$etch or over\$etching or (over adj etch) or (over adj etching))	USPAT	2003/08/04 14:17
-	3	(aluminum same(over\$etch or over\$etching or (over adj etch) or (over adj etching))) and ("3-D" or (three adj dimension))	USPAT	2003/08/04 15:33
-	7081	(over\$etch or over\$etching or (over adj etch) or (over adj etching)) and (semiconductor or wafer or substrate)	USPAT	2003/08/04 15:34

-	4694	((over\$etch or over\$etching or (over adj etch) or (over adj etching)) and (semiconductor or wafer or substrate)) and control\$3	USPAT	2003/08/04 15:35
-	2360	((over\$etch or over\$etching or (over adj etch) or (over adj etching)) and (semiconductor or wafer or substrate)) and control\$3)	USPAT	2003/08/04 15:36
-	1310	((((over\$etch or over\$etching or (over adj etch) or (over adj etching)) and (semiconductor or wafer or substrate)) and control\$3) and aluminum)	USPAT	2003/08/04 15:36
-	176	((((over\$etch or over\$etching or (over adj etch) or (over adj etching)) and (semiconductor or wafer or substrate)) and control\$3) and aluminum) and ("3-D" or "three-D" or dimension or dimensional))	USPAT	2003/08/04 16:12
-	7556	((((over\$etch or over\$etching or (over adj etch) or (over adj etching)) and (semiconductor or wafer or substrate)) and control\$3) and aluminum) and ("3-D" or "three-D" or (three adj dimension) or (three adj dimensional))	USPAT	2003/08/04 16:25
-	599	((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) and (etch or etching))	USPAT	2003/08/04 16:13
-	277	((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) and (etch or etching)) and aluminum	USPAT	2003/08/04 16:13
-	199	(((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) and (etch or etching)) and aluminum) and semiconductor	USPAT	2003/08/04 16:13
-	384	((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) with model	USPAT	2003/08/04 16:46
-	13	((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled) with model) and (etch or etching))	USPAT	2003/08/04 16:22
-	2679	((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) and model	USPAT	2003/08/04 16:26
-	514	((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) same model	USPAT	2003/08/04 16:26
-	13	(((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) same model) and (etch or etching))	USPAT	2003/08/04 16:26
-	161	(((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) and model) and (etch or etching))	USPAT	2003/08/04 16:27
-	53	((("3-D" or "three-D" or (three adj dimension) or (three adj dimensional)) with (control or controlling or controller or controled)) same (etch or etching))	USPAT	2003/08/04 16:47